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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): NABESHIMA et al.	Atty. Docket: PA214WP002
Serial No.: 10/598,933	Group Art Unit: n/a
Filed: 14 September 2006	Examiner: n/a
Title: SEMICONDUCTOR WAFER INSPECTION DEVICE AND METHOD	

Date: March 19, 2007

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450
Mail Stop: Amendment

PRELIMINARY AMENDMENT

Sir:

Pursuant to 37 C.F.R. 1.115 and M.P.E.P. § 714.09, the Applicant wishes to file this
PRELIMINARY AMENDMENT to the above-identified application.

Amendments to the Specification begin on page 2 of this paper.

Remarks begin on page 3 of this paper.